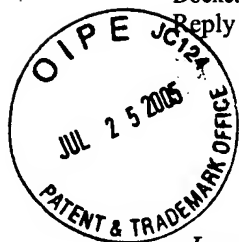


Appl. No.: 10/029,158
Amdt. dated July 22, 2005
Docket No.: A-69175-1/MSS (463035-650)
Reply to Office Action of March 22, 2005



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Nam P. Suh et al.

Serial No.: **10/029,158**

Filed: **December 21, 2001**

For: **APPARATUS AND METHOD FOR
CHEMICAL MECHANICAL
POLISHING OF SUBSTRATES**

Examiner: **RACHUBA, Maurina T.**

Art Unit: **3723**

Confirmation No.: **5210**

San Francisco, CA **94111**

Date: **July 22, 2005**

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Alexandria, VA 22313-1450

AMENDMENT/RESPONSE

Sir:

In response to the final Office Action mailed March 22, 2005, Applicants submit the following amendments and remarks. A petition for a one-month extension of time with the requisite deposit account fee authorization is enclosed herewith, bringing the period of response to July 22, 2005.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.